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Attention: Mail Stop AF Response Under 37 C.F.R. § 1.116 Expedited Procedure Requested Examining Group 2823

PATENT Customer No. 22,852 Attorney Docket No. 04329.2622

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)
Gaku MINAMIHABA, et al.	) Group Art Unit: 2823
Serial No.: 09/932,943	) Examiner: Lee, Hsien Ming
Filed: August 21, 2001	
For: SLURRY FOR CHEMICAL MECHANICAL POLISHING AND METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE	RECEIVED  JUL 30 2003  ECHHOLUSY CENTER
Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450	2003 ATER 2800
Sir:	

## AMENDMENT AFTER FINAL

In reply to the Final Office Action of April 25, 2003, with a period for response extending through July 25, 2003, Applicants propose amending the application as follows. Applicants also respectfully request the Examiner's reconsideration in view of remarks that follow:

FINNEGAN HENDERSON FARABOW GARRETT & DUNNER LLP

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## **IN THE CLAIMS:**

Please amend claims 18 and 23, as follows: